

## N THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of	)	
Nobuo SHIMAZU et al.	: )	Group Art Unit: 2881
Application No.: 09/732,928	)	Examiner: J.P. Hughes
Filed: December 11, 2000	)	Confirmation No. 2305
For: ELECTRON BEAM PROXIMITY EXPOSURE APPARATUS AND MASK UNIT THEREFOR	; ;	

## **CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Mail Stop Non-Fee Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on December

3. M. Mc Manus

## **AMENDMENT**

Mail Stop Non-Fee Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

The following is presented in response to the Examiner's Office Action dated September 30, 2003, in connection with the above captioned patent application..